



S/N 10/789,042

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Kie Y. Ahn et al.	Examiner:	Allan R. Wilson
Serial No.:	10/789,042	Group Art Unit:	2815
Filed:	February 27, 2004	Docket No.:	1303.050US2
Title:	ATOMIC LAYER-DEPOSITED LaAlO <sub>3</sub> FILMS FOR GATE DIELECTRICS		

AMENDMENT AND RESPONSE UNDER 37 CFR § 1.111

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

This responds to the Office Action dated on February 23, 2006. Please amend the above-identified patent application as follows.